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**José Sasián
Richard N. Youngworth**
Editors

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The CID Number appears on each page of the manuscript. The complete citation is used on the first page, and an abbreviated version on subsequent pages.

Contents

v	<i>Authors</i>
vii	<i>Conference Committee</i>
ix	<i>Introduction</i>

SESSION 1	ALIGNMENT AND TOLERANCING FOR ASPHERES AND FREEFORMS
------------------	---

9582 02	Freeform capability enabled by ISO 10110 [9582-1]
9582 03	Scanning pupil approach to aspheric surface slope error tolerancing in head-up display optics [9582-2]
9582 04	The need for fiducials on freeform optical surfaces [9582-3]
9582 05	Tolerancing aspheric surfaces in optical design [9582-4]

SESSION 2	TOLERANCE ANALYSIS
------------------	---------------------------

9582 06	Slope sensitivities for optical surfaces [9582-5]
9582 07	Tolerance analysis of optical systems using the Nijboer-Zernike approach (Invited Paper) [9582-6]
9582 08	Design and tolerance analysis of a transmission sphere by interferometer model [9582-7]

SESSION 3	ALIGNMENT ANALYSIS, HARDWARE, AND METROLOGY
------------------	--

9582 09	Measuring NIRCams position and orientation in 6 DOF using one reference mirror surface inside an environmental chamber [9582-9]
9582 0A	Characterization of cryo-vacuum chamber windows for NIRCams instrument alignment and testing [9582-8]
9582 0B	Dynamic alignment, tolerances, and metrology fundamentals at the nano and micro scales (Invited Paper) [9582-10]
9582 0C	1μm adjustment-tolerance for high-precision helical laser drilling [9582-11]

SESSION 4 STATE ESTIMATION IN OPTICAL ALIGNMENT

9582 0D **Disruptive advancement in precision lens mounting** [9582-20]

9582 0F **State estimation in optical system alignment using monochromatic beam imaging**
[9582-13]

POSTER SESSION

9582 0I **Analysis of alignment tolerance of focal plane assembly of a telescope** [9582-16]

Authors

Numbers in the index correspond to the last two digits of the six-digit citation identifier (CID) article numbering system used in Proceedings of SPIE. The first four digits reflect the volume number. Base 36 numbering is employed for the last two digits and indicates the order of articles within the volume. Numbers start with 00, 01, 02, 03, 04, 05, 06, 07, 08, 09, 0A, 0B...0Z, followed by 10-1Z, 20-2Z, etc.

Aikens, David M., 02
Anctil, Geneviève, 0D
Andersen, Torben B., 09, 0A
Brunelle, Matthew, 04
Chang, Shenq-Tsong, 0I
Chen, Fong-Zhi, 0I
Côté, Patrice, 0D
Desnoyers, Nichola, 0D
Doucet, Michel, 0D
Fang, Joyce, 0F
Fornaroli, C., 0C
Fuchs, U., 05
Gauvin, Jonny, 0D
Gillner, A., 0C
Hanft, Marco, 07
Ho, Cheng-Fong, 08
Holtkamp, J., 0C
Hsu, Ming-Ying, 0I
Hsu, Wei-Yao, 08
Huang, Chien-Yao, 08
Huang, Ting-Ming, 0I
Kiontke, Sven R., 02
Lamontagne, Frédéric, 0D
Lin, Wen-Lung, 08
Lin, Yu-Chuan, 0I
Medicus, Kate, 04
Nelson, Jessica D., 04
Peng, Wei-Jei, 08
Rogers, John R., 06
Ryll, J., 0C
Savransky, Dmitry, 0F
Schweiger, Paul F., 09, 0A
Silberman, Donn M., 0B
Sivokon, V. P., 03
Youngworth, Richard N., 02
Yu, Zong-Ru, 08
Zibner, F., 0C

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- 1 Alignment and Tolerancing for Aspheres and Freeforms
Sen Han, University of Shanghai for Science and Technology (China)
- 2 Tolerance Analysis
José Sasián, College of Optical Sciences, The University of Arizona
(United States)

- 3 Alignment Analysis, Hardware, and Metrology
Richard N. Youngworth, Riyo LLC (United States)
- 4 State Estimation in Optical Alignment
Marco Hanft, Carl Zeiss AG (Germany)

Introduction

It is with great pleasure that we write this introduction to the proceedings of a successful Optical System Alignment, Tolerancing, and Verification conference in 2015. This ninth conference showed signs of great change and increasing capability in the field. The optics and photonics community again bestowed upon us the honor of editing a set of excellent talks and posters into this proceedings volume. The attendance at our Sunday sessions showed that the conference topics are of current interest, useful, and of central importance to the community.

This year's conference had four great sessions. The opening session had many attendees interested in two papers on freeform optics and asphere tolerancing respectively. The second session continued the theme of tolerancing with discussions on slope sensitivities for optical surfaces, a tolerance analysis tutorial-style paper, and a tolerance analysis paper for a transmission sphere. The first afternoon session had two linked alignment and verification papers for the key NIRCam instrument being integrated into the James Webb Space Telescope. The third talk provided an overview and hardware for alignment, tolerances, and metrology fundamentals at the nano and microscales. The last talk in the first afternoon session discussed a one micrometer adjustment for helical laser drilling. The fourth session concluded the oral conference program with a talk that gave an overview of lens mounting methods in the context of a new precision optical mounting method, state estimation in optical system alignment, and alignment estimation performance analysis for a three mirror anastigmat. The poster session had two papers total. The first paper covered an analysis of the alignment tolerance of a focal plane assembly in a telescope and the second discussed development of a large ground-based fast steering mirror assembly. The reader will enjoy and benefit from reading these papers.

As chairs of a tight-knit and popular conference, we once again must humbly thank our program committee for the support they have continued to provide this conference. We are also grateful to all of the presenters for sharing their work, the audience for participating and helping to facilitate conversations at the conference, and to SPIE for providing us the opportunity to cover these important topics at Optical System Alignment, Tolerancing, and Verification IX in 2015.

We are happy and excited to chair this conference again in 2016. We encourage everyone interested in any related research or development projects to please submit their work and attend the conference. Without great participation this conference would not have a strong tradition of keeping the important topics of alignment, tolerancing, and verification at the forefront of the optics and

photonics conference. Please feel free to contact us or anyone on our program committee if you have any questions. We look forward to another successful conference in 2016.

José Sasián
Richard N. Youngworth